

Capacitance of Silicon Pixels

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PIXEL 2000 Conference

5 June 2000

Overview

- Goals of the measurements
- Devices and simulation
- Results

Introduction and Goals of the Measurements

The total capacitance of a pixel sensor affects its detector's **noise**. The ratio,

$(\text{Capacitance to neighbors}) / (\text{Total capacitance})$ affects the **cross coupling** between channels.

The total capacitive load that a pixel sensor presents to the front end electronics includes

- **bump pad**
- **preamplifier input transistor**
- capacitance to neighbors (“**inter-pixel contribution**”)
- **backplane** contribution

This study examines inter-pixel + backplane capacitance.

For application to LHC + Tevatron experiments, we include the effects of

- radiation damage and
- low temperature operation.

The project:

1. Study a set of test structures whose design is simple enough that the measurement of the capacitance between a pixel and all neighbors is unambiguous.

→“The LBNL Test Structures”

2. Model the capacitance of these test structures to understand systematics and calibrations.

3. Using the same calibration procedure + measurement setup (i.e., systematics), study a set of pixel structures more like those in a physics detector. These sensors use p-stop isolation.

→“Structure 6”

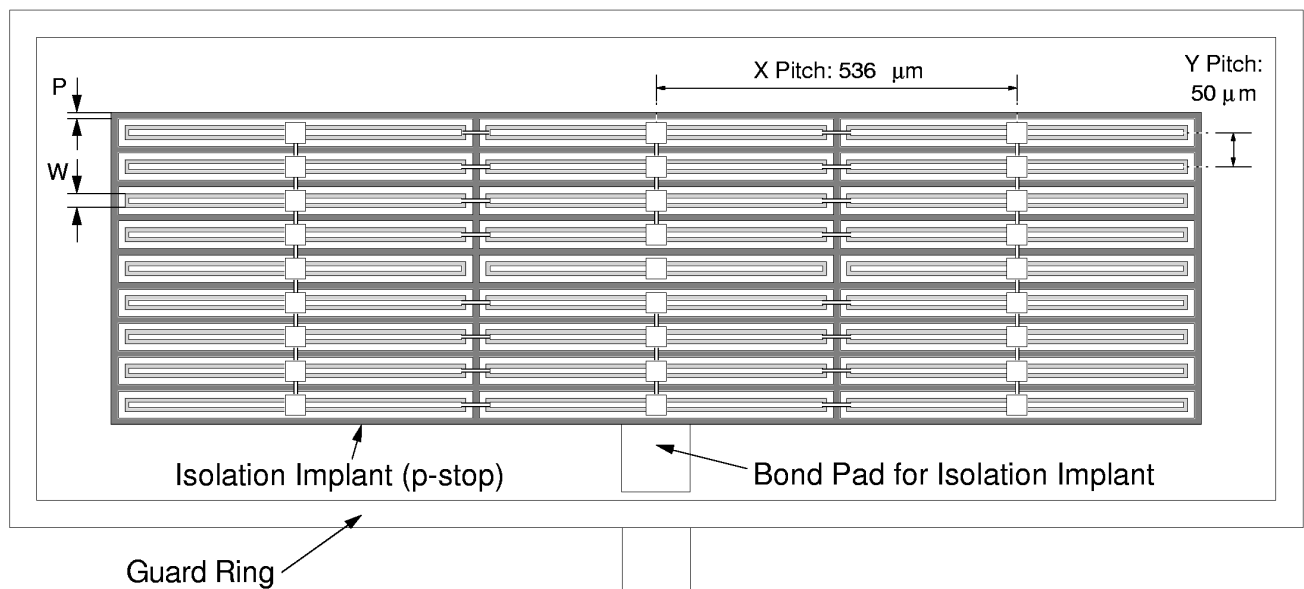
4. Measure the inter-pixel and backplane capacitance of ATLAS prototype (p-spray) sensors.

5. Investigate the dependence of the capacitance on operating temperature.

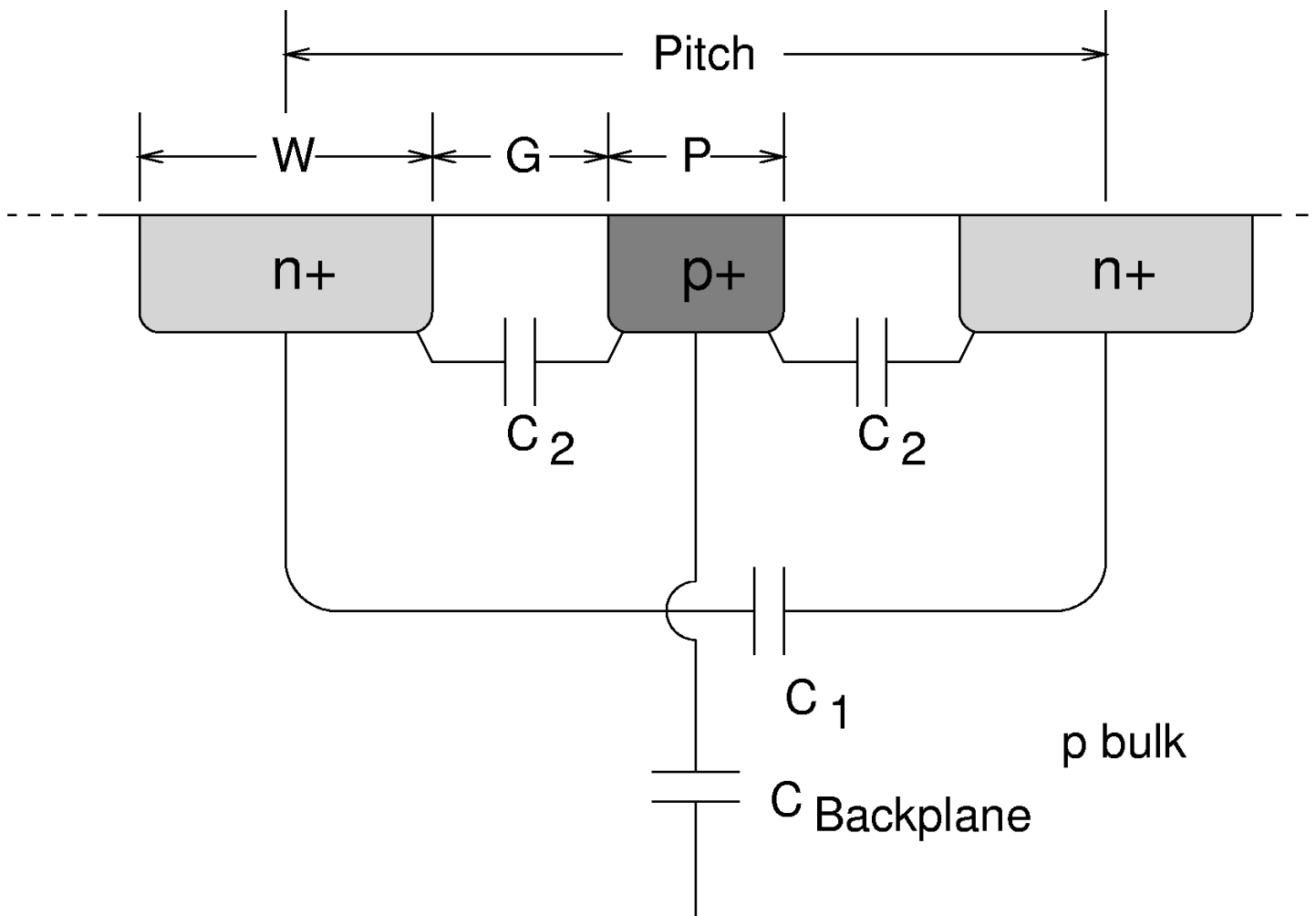
The LBNL Test Structures

Designed and fabricated by S. Holland, LBNL

- versions in *p-on-n* and *n-on-p*
- each structure has six 3×9 arrays
- in each array, the center pixel is isolated and the neighbors are ganged. All neighbors can be biased with 1 probe.
- Pitch: $50 \mu\text{m} \times 536 \mu\text{m}$



- 5 n -bulk and 5 p -bulk were studied
- The p -bulk devices examine common p -stops of various widths (“P”) and gaps (“G”).



Feature dimensions of the LBNL Test Structures, in microns. The “g” is the total gap between charge collection implants.

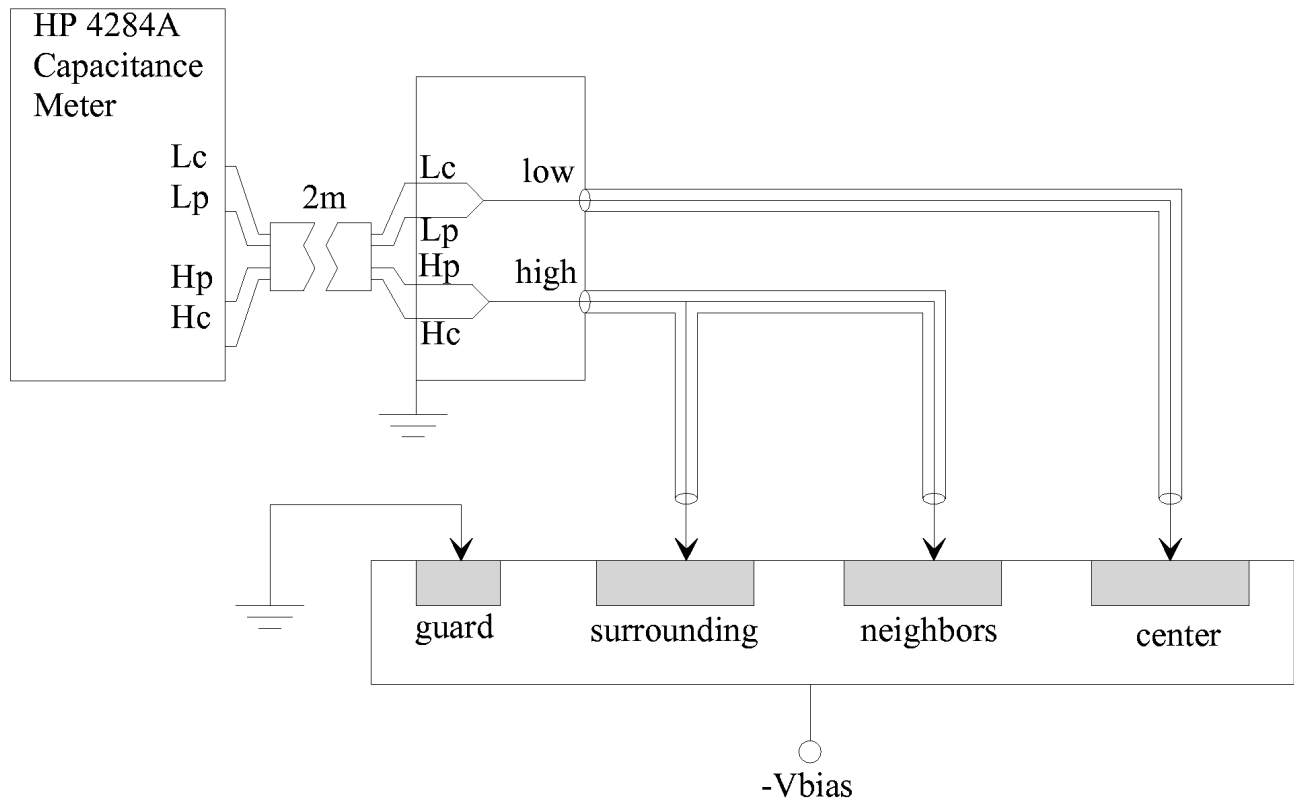
n-bulk:

Array #	<i>p</i> Width (W)	Total Gap (g)
2	38	12
3	32	18
4	23	27
5	20	30
6	14	36

p-bulk:

Array #	<i>n</i> Width (W)	Total Gap (g)	p-stop Width (P)
2	38	8	4
3	32	12	6
4	23	19	8
5	20	20	10
6	14	24	12

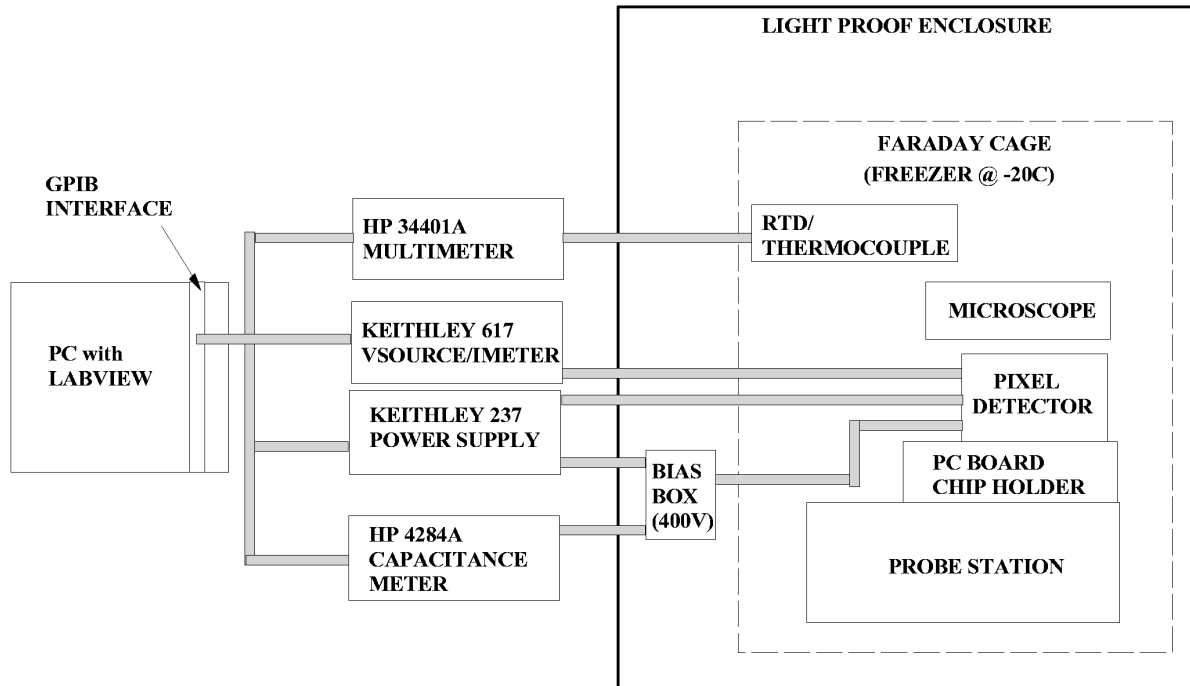
Measurement Setup



- The LCR meter supplies a 250 mV rms signal on HIGH. Amplitude and phase are measured on LOW.
- To measure inter-pixel capacitance, the pixel of interest is connected to LOW, all others to HIGH.

Test stand

DETECTOR PROBING TEST STAND



- Prior to measurement, the probe attached to LOW is raised a few microns above the pixel, the sensor biased to $\sim 100\text{V}$ (overdepletion), and the meter set to OPEN mode. This procedure measures all parasitic capacitances. The result is stored as a subtractable reference.
- Residual parasitic capacitance after OPEN correction: $< 2\text{ fF}$.

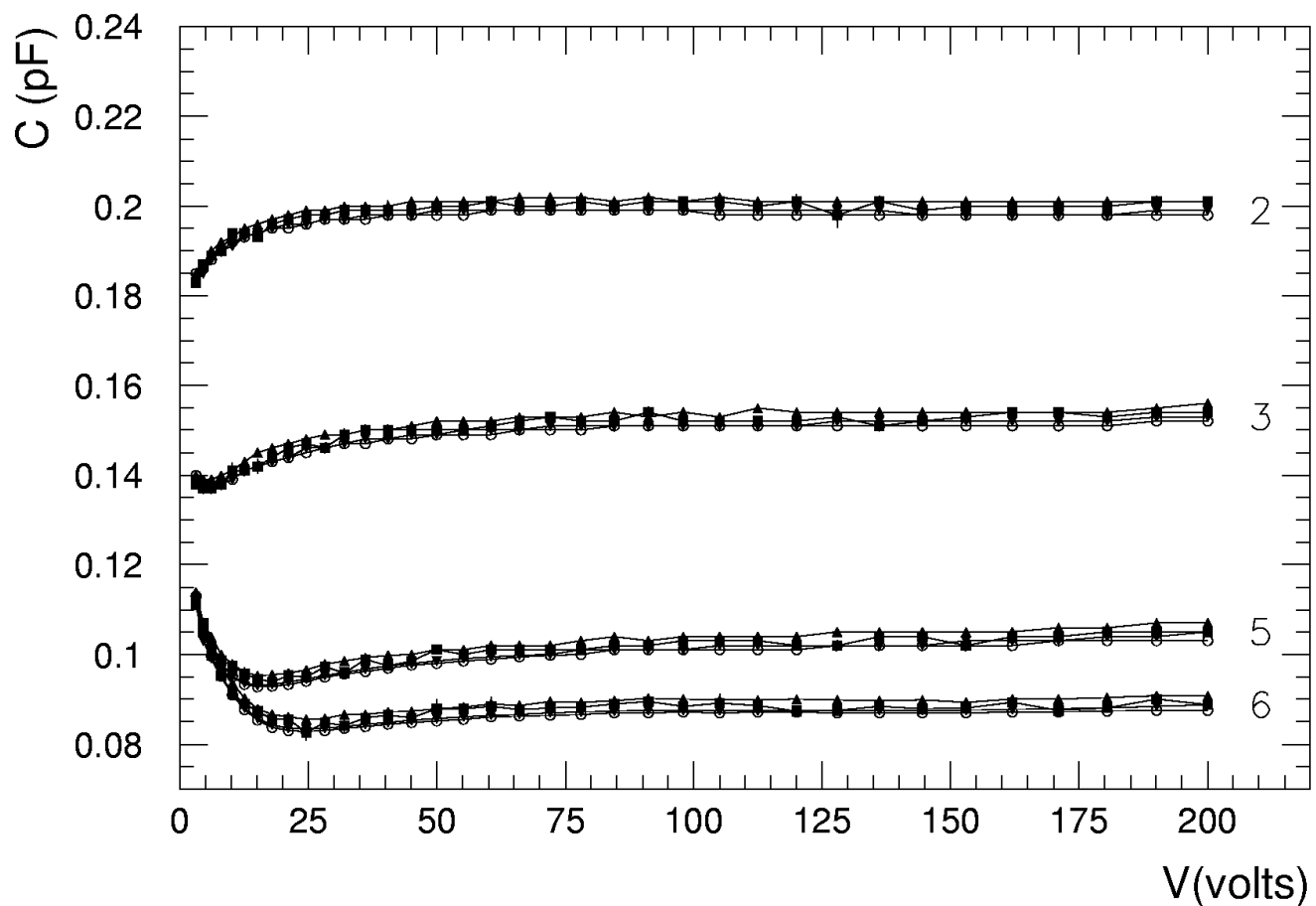
Combined uncertainty per measurement:

- Statistical: 3fF
 - based on the standard deviation of repeated measurements at 1MHz and 200V.
- Systematic: 1fF
 - conservative measure of the voltage dependence of the OPEN correction
- Systematic: 3fF
 - based on the accuracy reported for this meter type (HP 4284A).
- Systematic on irradiated sensors only: 1-13fF
 - in some cases, highly irradiated sensors risked thermal runaway if operated at room temperature at voltages required to plateau their $C_{\text{inter-pixel}}$ -V curve. For them, the minimum $C_{\text{inter-pixel}}$ was determined by extrapolation.

LBNL Test Structure Measurement Results:

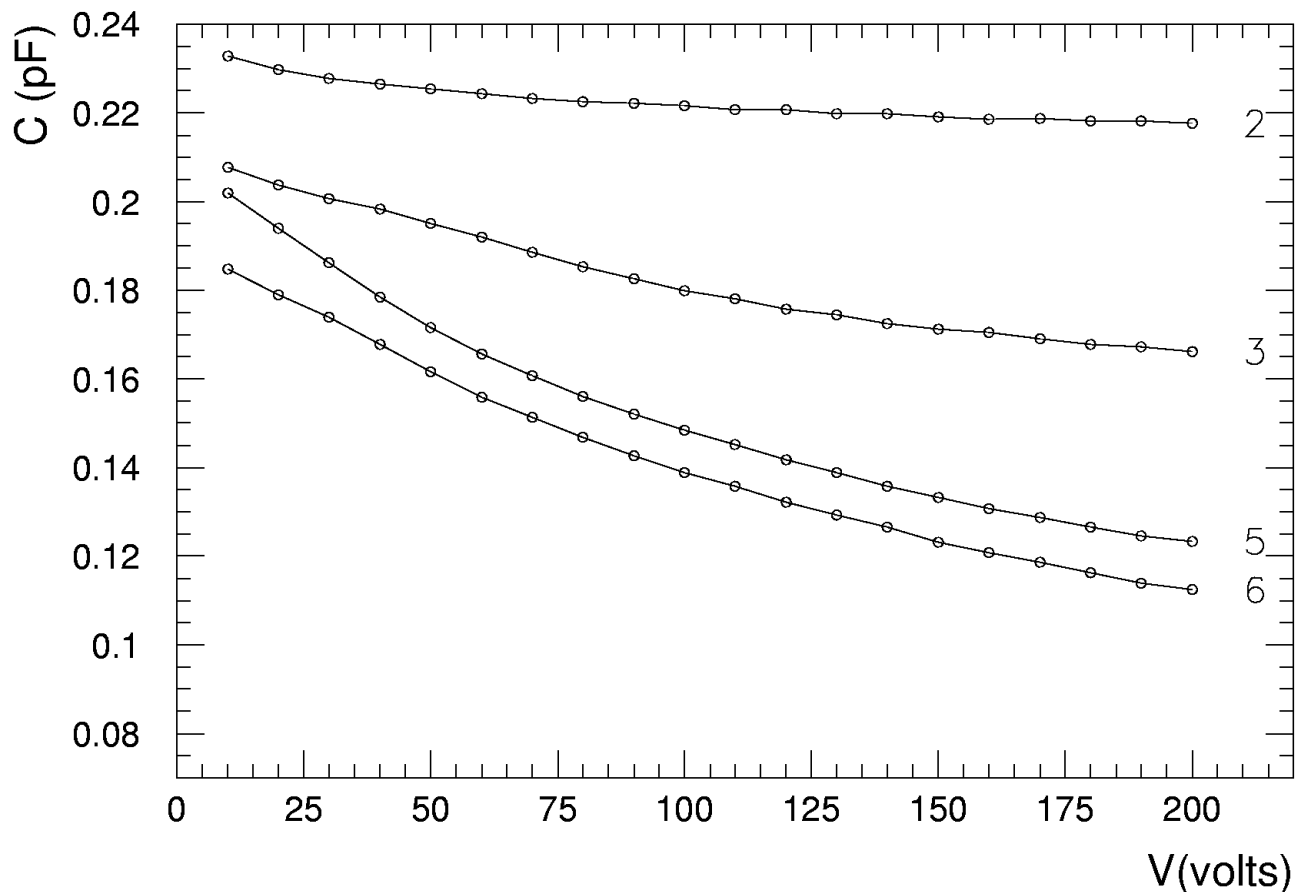
- for p -on- n and n -on- p
- for frequencies of 3 kHz, 10 kHz, 100 kHz, and 1 MHz
- unirradiated and after $4.8 \times 10^{13} \text{ cm}^{-2}$ (1 MeV neutron equivalent) fluence

A typical measurement: the inter-pixel capacitance of unirradiated *p*-type LBNL test structure arrays:



Typical data requiring extrapolation to the minimum $C_{\text{inter-pixel}}$: *p*-type test structures irradiated to fluence 4.8×10^{-13} 1-MeV neutron-equivalent/cm². The data are well fit by

$$C_{\text{inter-pixel}} = A + e^{B-Dx}$$



Summary of inter-pixel capacitance measurements on LBNL test structures :

Array	C_{unirrad} (fF)	C_{irrad} (fF)
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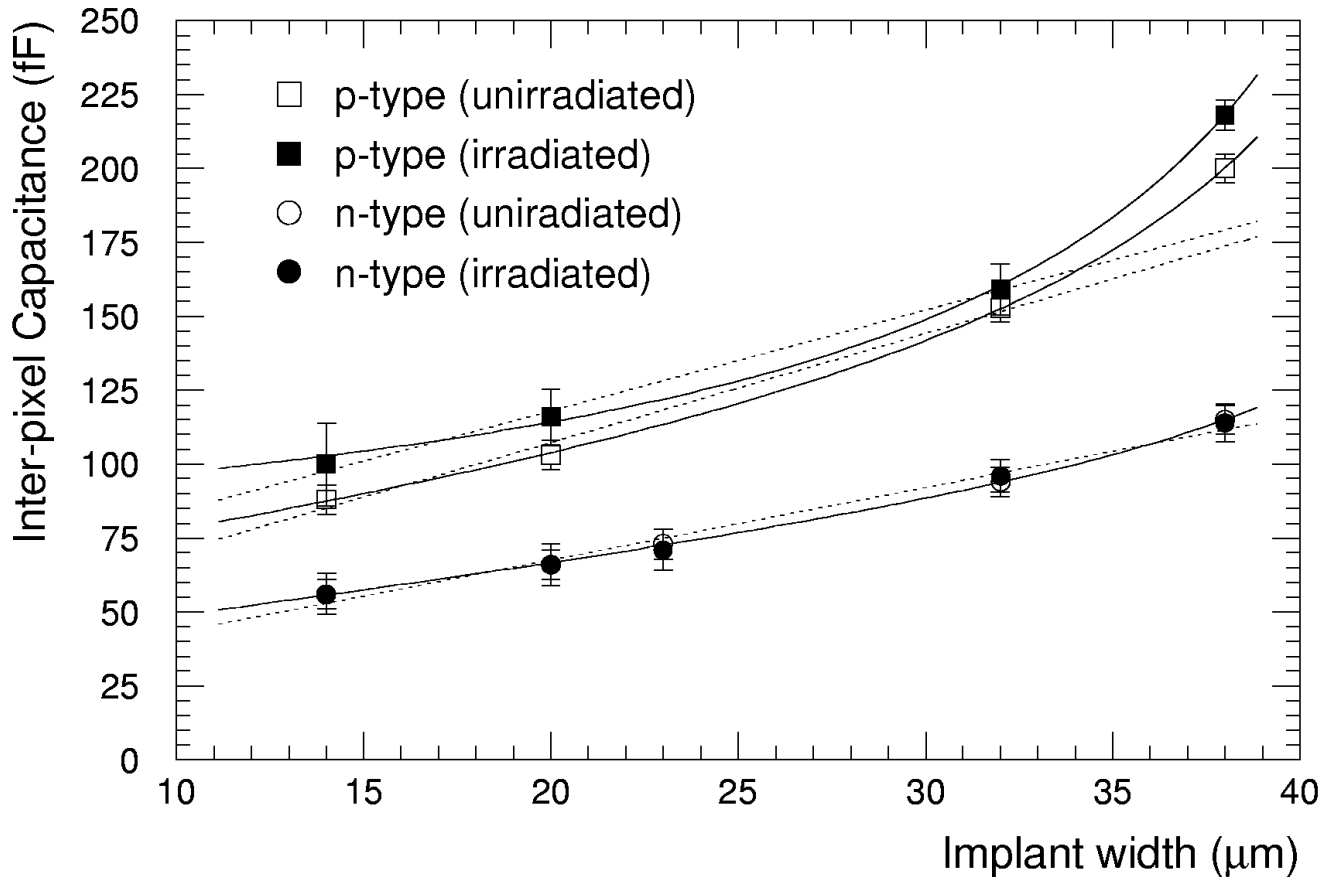
n-type:

2	115 ± 5	114 ± 7
3	94 ± 5	96 ± 6
4	73 ± 5	71 ± 7
5	66 ± 5	66 ± 7
6	56 ± 5	56 ± 7

p-type:

2	200 ± 5	218 ± 5
3	153 ± 5	159 ± 9
5	103 ± 5	116 ± 10
6	88 ± 5	100 ± 14

Inter-pixel capacitance versus implant width:



Dotted line: linear function

Solid line: $C_{\text{inter-pixel}} = A + (BW / \rho) + (D / g)$,

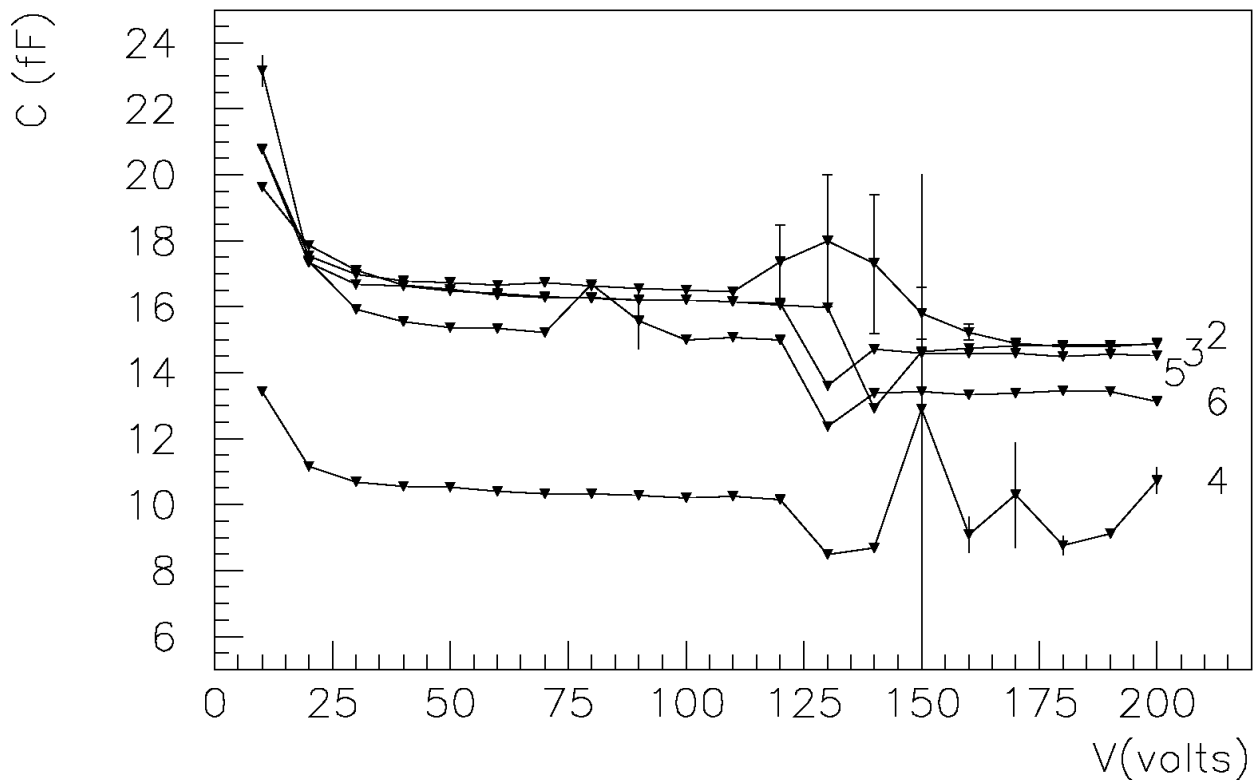
where W = implant width

ρ = pitch

g = gap between charge collection implants

Pixel backplane capacitance

- similar to $C_{\text{inter-pixel}}$ measurement, but with LOW connected to the center pixel and HIGH connected to the back side.
- A typical measurement for unirradiated *n*-type:



Summary of backplane capacitance measurements on unirradiated LBNL test structures:

Array	$C_{\text{backplane}}$ (fF)
-------	-----------------------------

n-type

2	15 ± 5
3	15 ± 5
4	11 ± 5
5	15 ± 5
6	13 ± 5

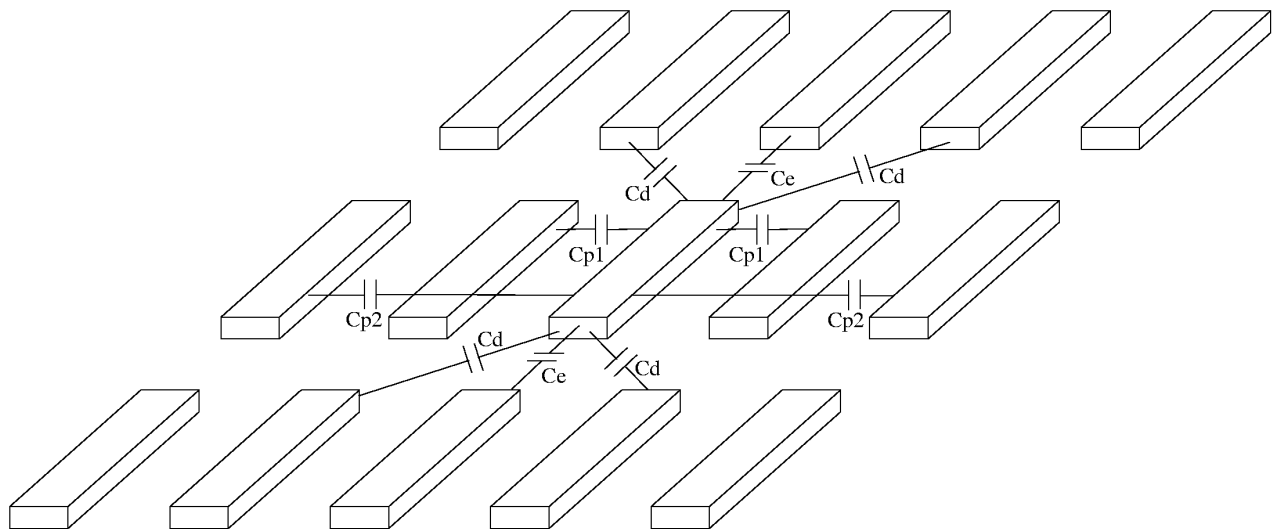
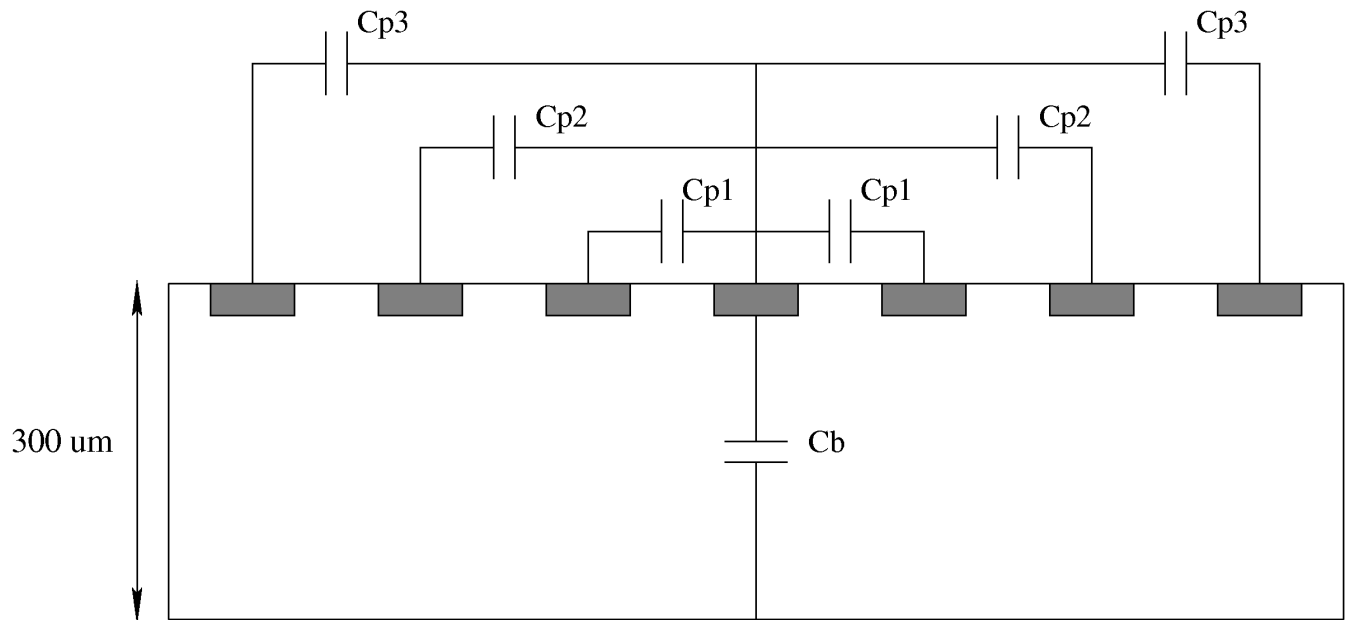
p-type

2	18 ± 5
3	16 ± 5
4	11 ± 5
6	21 ± 5

Simulation of the LBNL Test Structures

- Results of 2-D simulators HSPICE and IES Electro and 3-D simulator IES Coulomb were compared to interpret the measurements, indicate the precision of simulation, and estimate the size of contribution of non-adjacent neighbors.
- The simulators take as input the geometry of the sensor and information about the dielectrics and solve the electrostatic field equations.

Geometries used in the simulation:



Comparison of predictions to measurements:

$C_{backplane}$ of unirradiated n-type sensors:

Array	$C_{meas}(fF)$	$C_{sim-IES2D}(fF)$	$C_{sim-IES3D}(fF)$
2	15 ± 5	10 ± 2	13 ± 3
3	15 ± 5	10 ± 2	13 ± 3
4	11 ± 5	10 ± 2	12 ± 2
5	15 ± 5	10 ± 2	12 ± 2
6	13 ± 5	10 ± 2	12 ± 2

$C_{inter-pixel}$ of unirradiated n-type sensors:

Array	$C_{meas}(fF)$	$C_{sim-HSPICE}(fF)$	$C_{sim-IES2D}(fF)$	$C_{sim-IES3D}(fF)$
2	115 ± 5	130 ± 46	109 ± 38	124 ± 43
3	94 ± 5	115 ± 40	91 ± 32	111 ± 39
4	73 ± 5	95 ± 32	78 ± 27	93 ± 33
5	66 ± 5	89 ± 31	72 ± 25	87 ± 30
6	56 ± 5	75 ± 26	66 ± 23	76 ± 27

Implications:

- Agreement between simulations and measurements within 30%
- Contribution of capacitance from next-to-nearest neighbors: $\sim 11\%$
- Contribution of capacitance from next-to-next-to-nearest neighbors: $\sim 7\%$

Implications of the LBNL Test Structure studies:

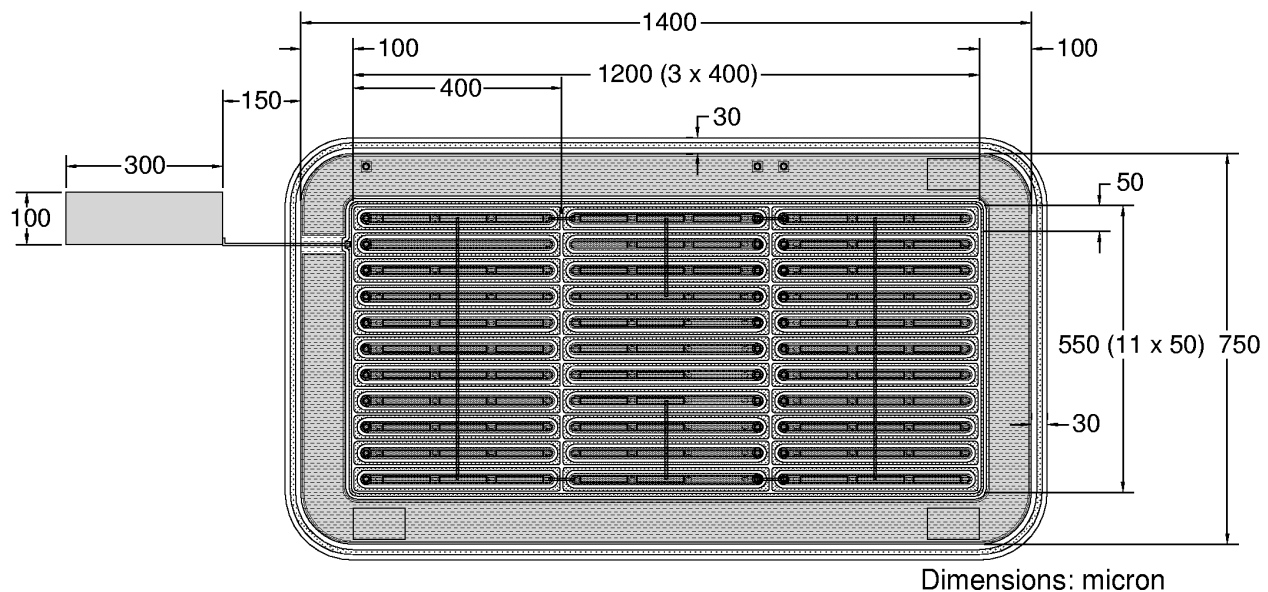
- good agreement between measurement and simulation suggests that the measurement procedure may be used for values in the range 10 fF - a few hundred fF.
- For sensors with 50 μm pitch, 300 μm thickness, typical ratio $C_{\text{backplane}}/C_{\text{inter-pixel}}$ is 10-25%.

We next apply the procedure to a set of more realistic pixel arrays, **Structure 6...**

Structure 6

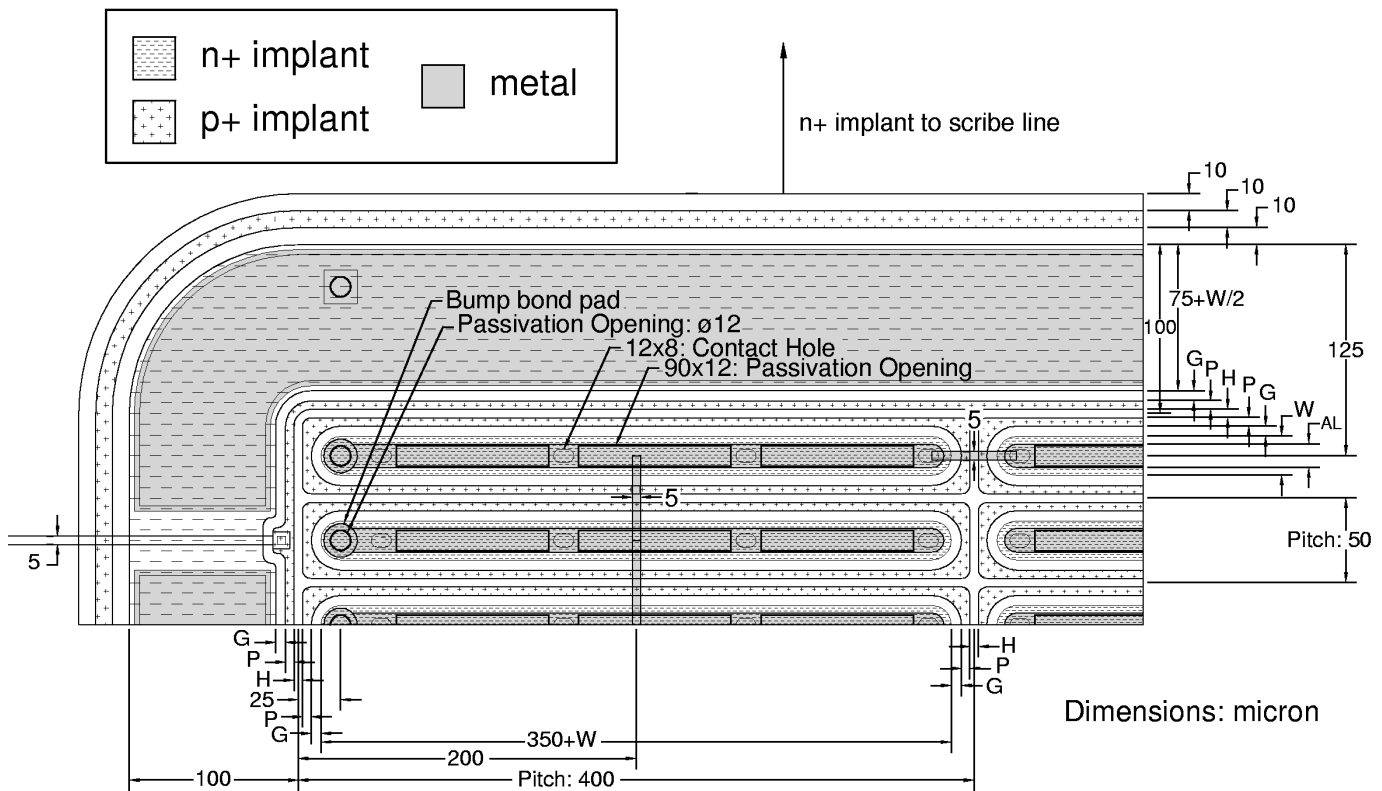
Designed by G. Gorfine at Univ. of New Mexico, fabricated at CiS and Seiko

- *n*-on-*n*, 300 μm thick
- eleven 3×11 arrays, each with the center 3 pixels isolated and neighbors connected

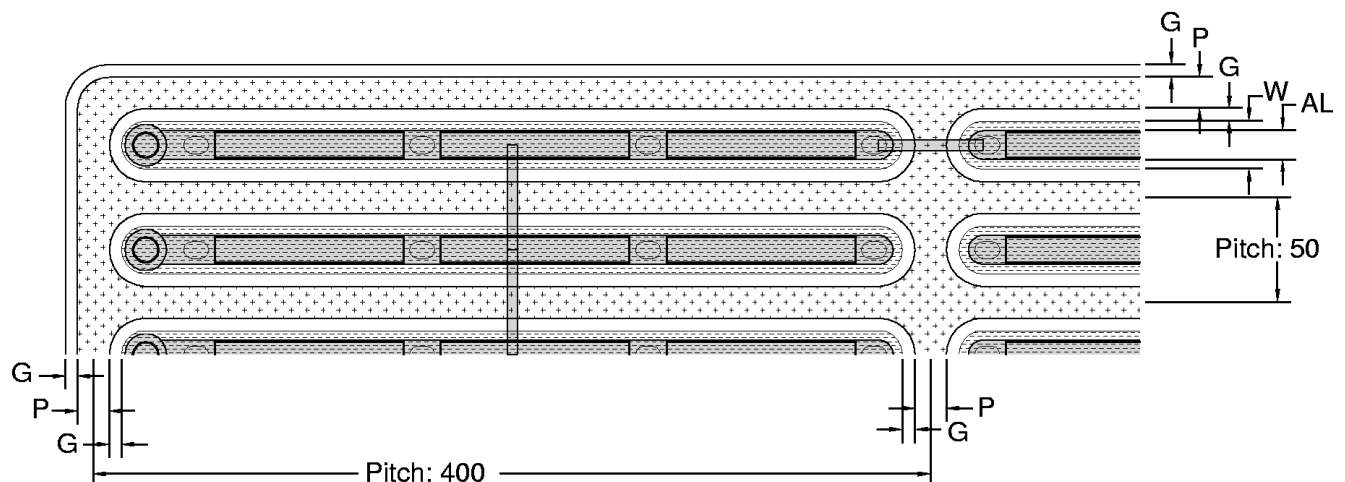


- 3 p-stop designs were studied:

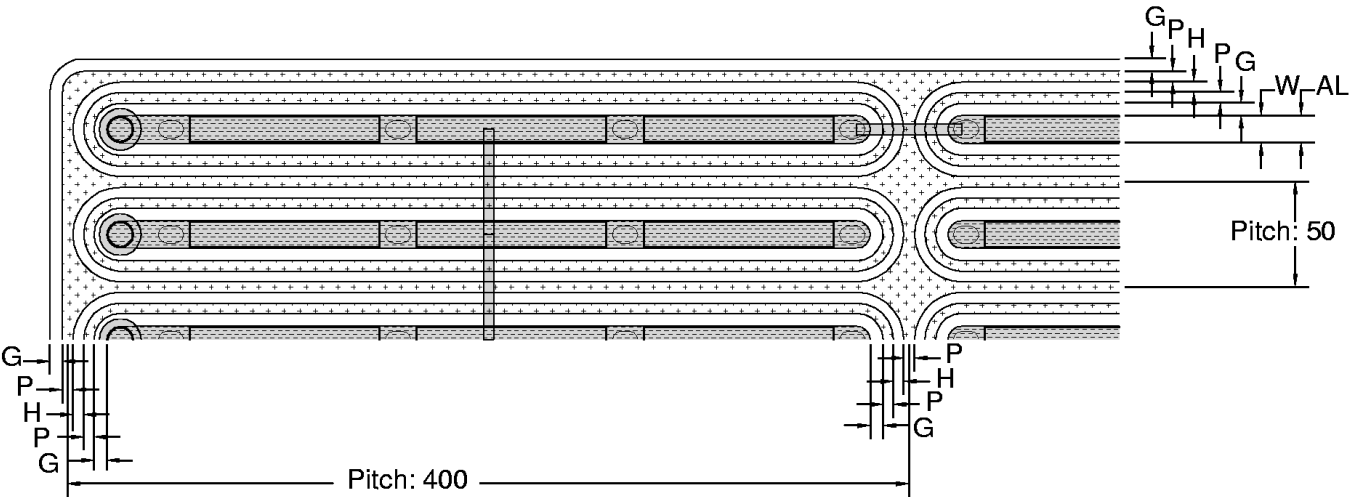
- atoll:



- common:



•combined:



Geometries tested:

Array	p-stop Design	W	P	G	H	g
1	Atoll	23	5	6	5	17
2	Atoll	23	5	6	5	17
3	Atoll	16	5	6	12	24
4	Atoll	15	5	10	5	25
5	Atoll	19	5	8	5	21
6	Combined	13	5	6	5	22
7	Common	33	5	6	x	12
8	Common	28	10	6	x	12
9	Common	23	15	6	x	12
10	Common	24	10	8	x	16
11	Common	20	10	10	x	20

W = n -implant width

P = p-stop width

G = gap between n - and p -implants

H = gap between neighboring p -implants

g = total gap between charge collection implants

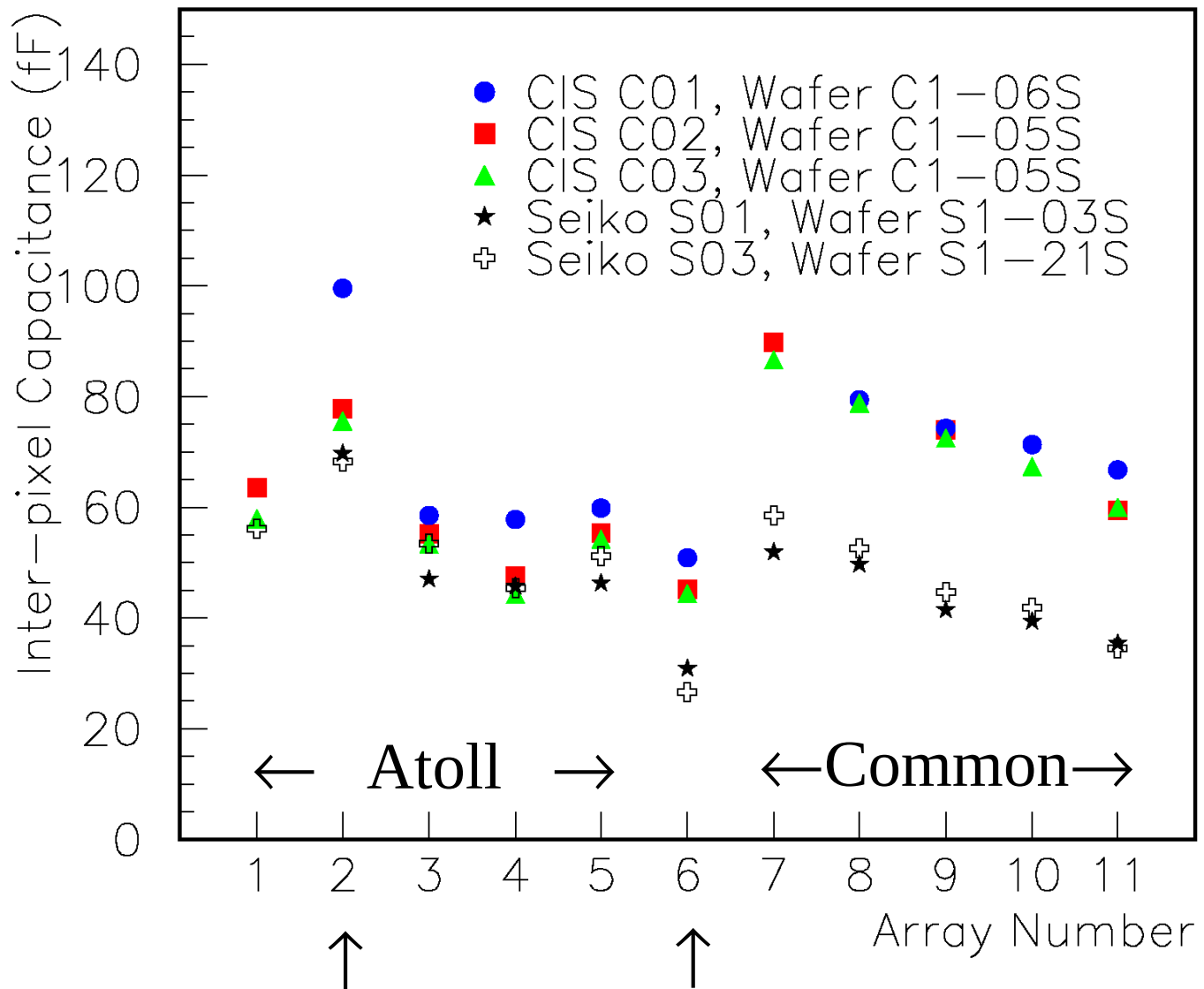
All arrays except #2 have metal narrower than implant.

We did not simulate Structure 6. However, Array 1 of Structure 6 has the same geometry as Tile 1, a design using p-stops that was examined in the First ATLAS Pixel Sensor Prototypes. The p-stop design was studied in a device simulation whose results are published in T. Rohe, et al., NIM A 409, 224 (1998).

From T. Rohe et al., Table 1:

Capacitance (fF)	p-spray Option (d)	p-stop Design
Total	128	86.4
1st neighbor	54.0	33.0
2nd neighbor	3.96	3.6
Backplane	7.35	7.4

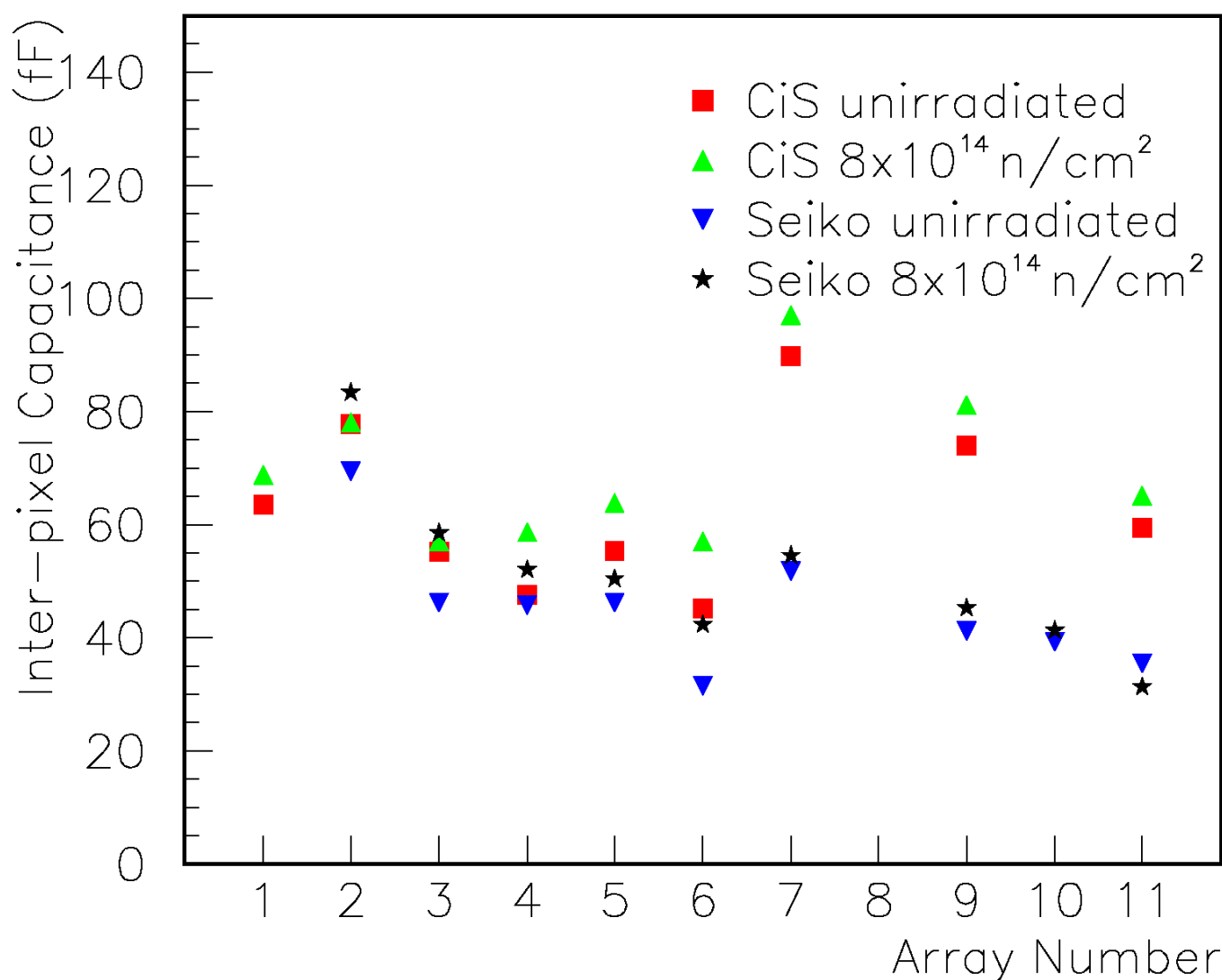
Inter-pixel capacitance of unirradiated Structure 6 arrays for different p-stop designs:



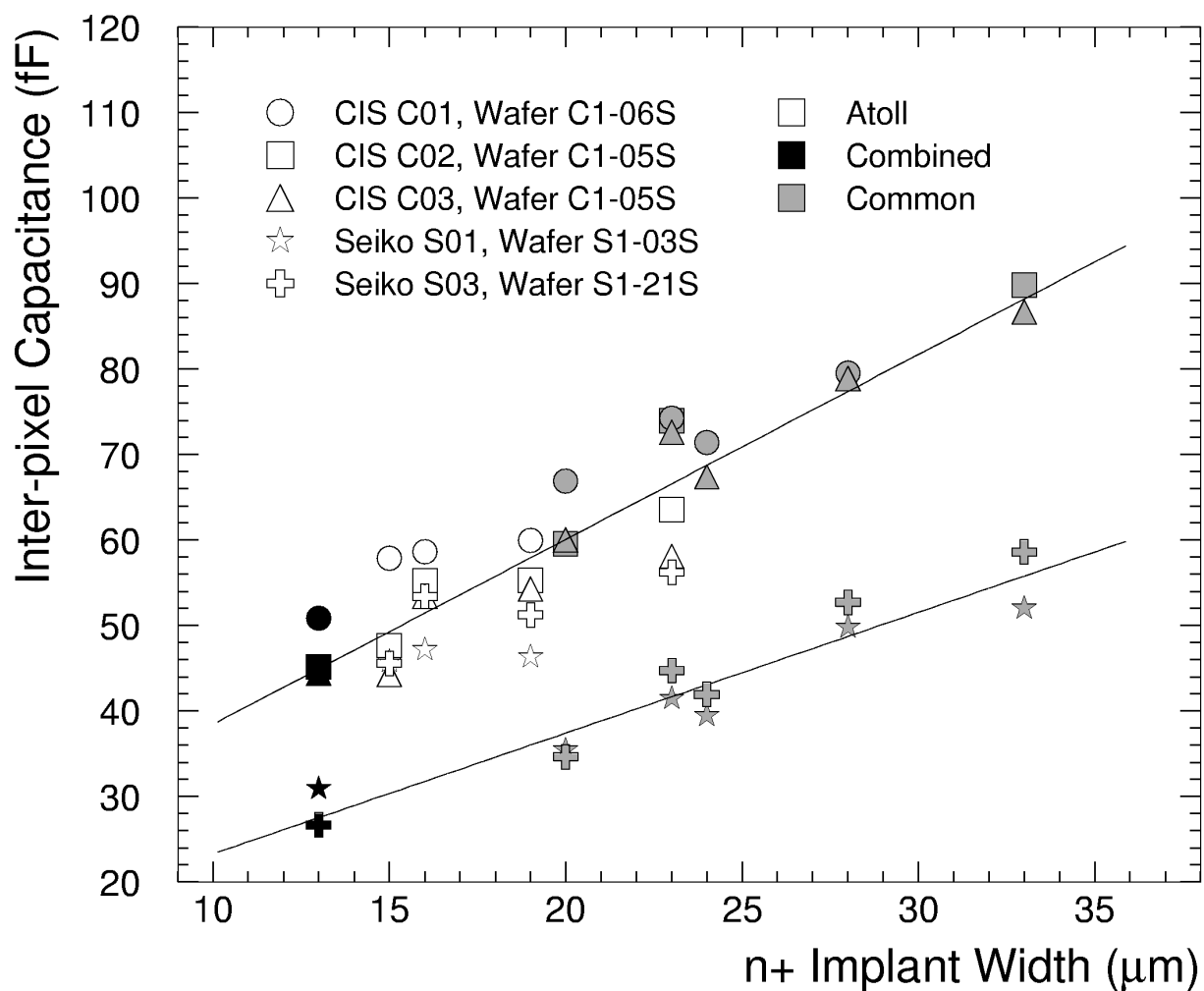
Metal wider
than implant

Combined

Inter-pixel capacitance of Structure 6 arrays for different p-stop designs, before and immediately after irradiation:



Inter-pixel capacitance versus implant width for unirradiated Structure 6 sensors of pitch 50 μm :

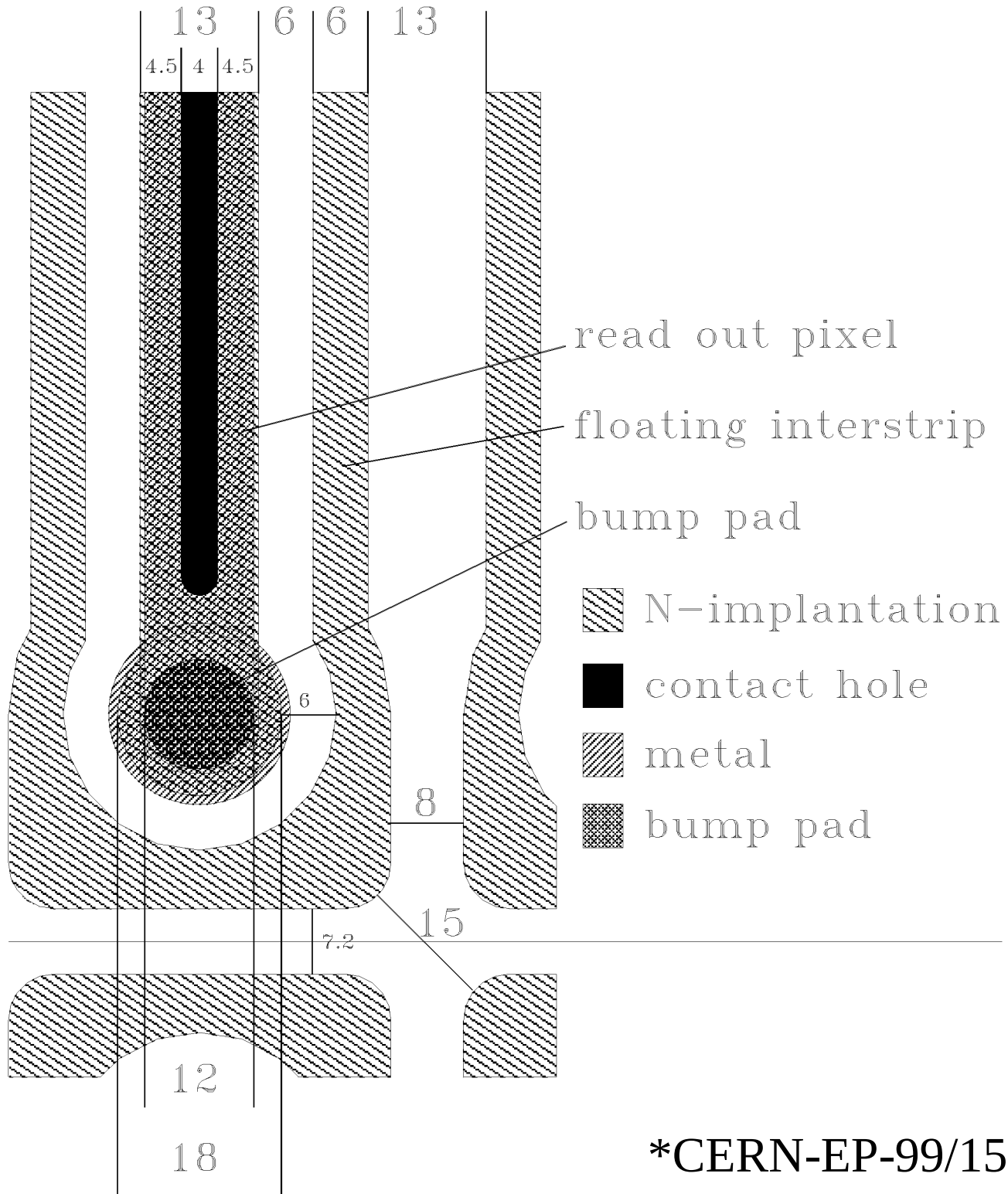


We next apply the procedure to the ATLAS prototype pixel sensors with p-spray* isolation...

*R. H. Richter et al., NIM A 377, 412 (1996).

The ATLAS ST2 Prototype Sensor*

Designed by R. Richter, T. Rohe, et al.;
fabricated at CiS and Seiko

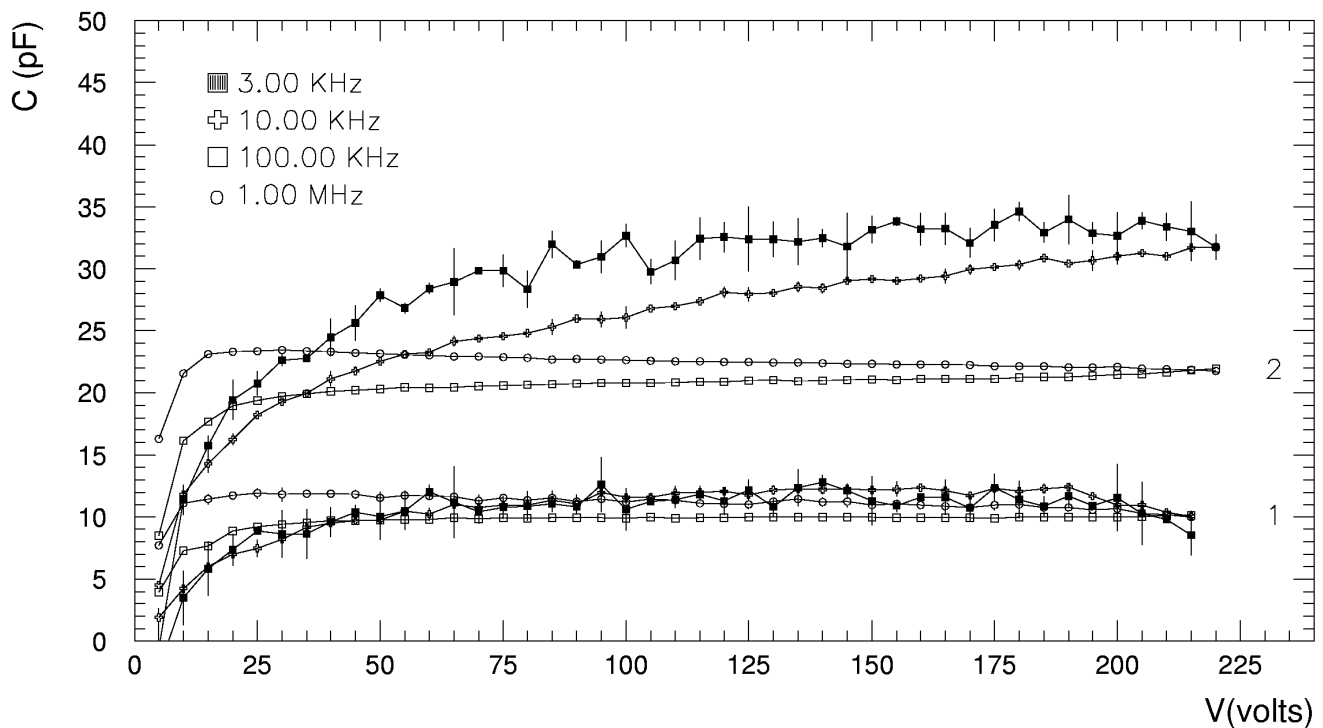


*CERN-EP-99/152

Inter-pixel capacitance of a p-spray ST2 sensor irradiated with 1.3×10^{14} (55 MeV p)/cm²:

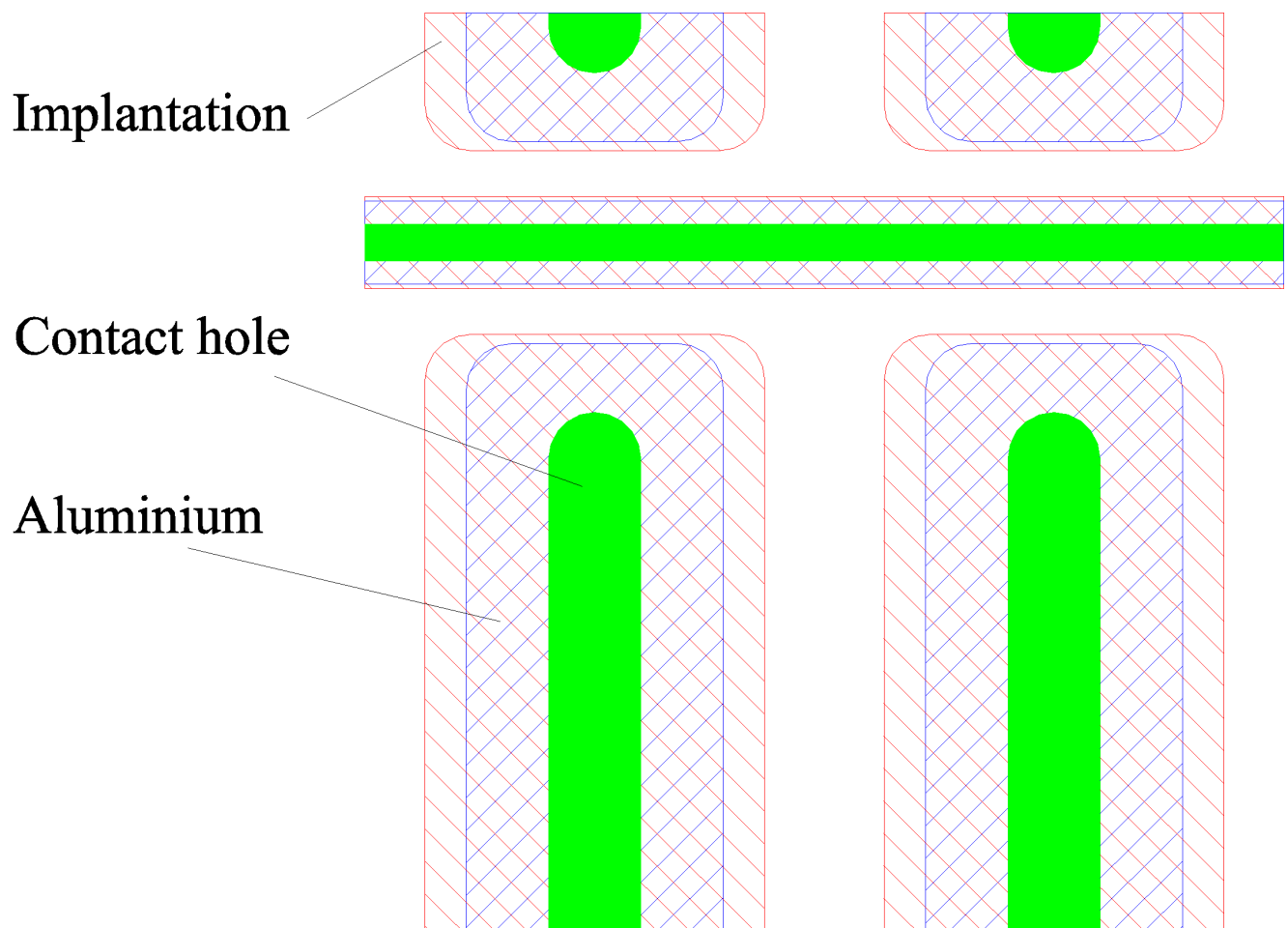
Lower curve: 1 nearest neighbor

Upper curve: both nearest neighbors



The ATLAS SSG Prototype Sensor*

Designed by R. Richter, T. Rohe, et al.;
fabricated at CiS and Seiko

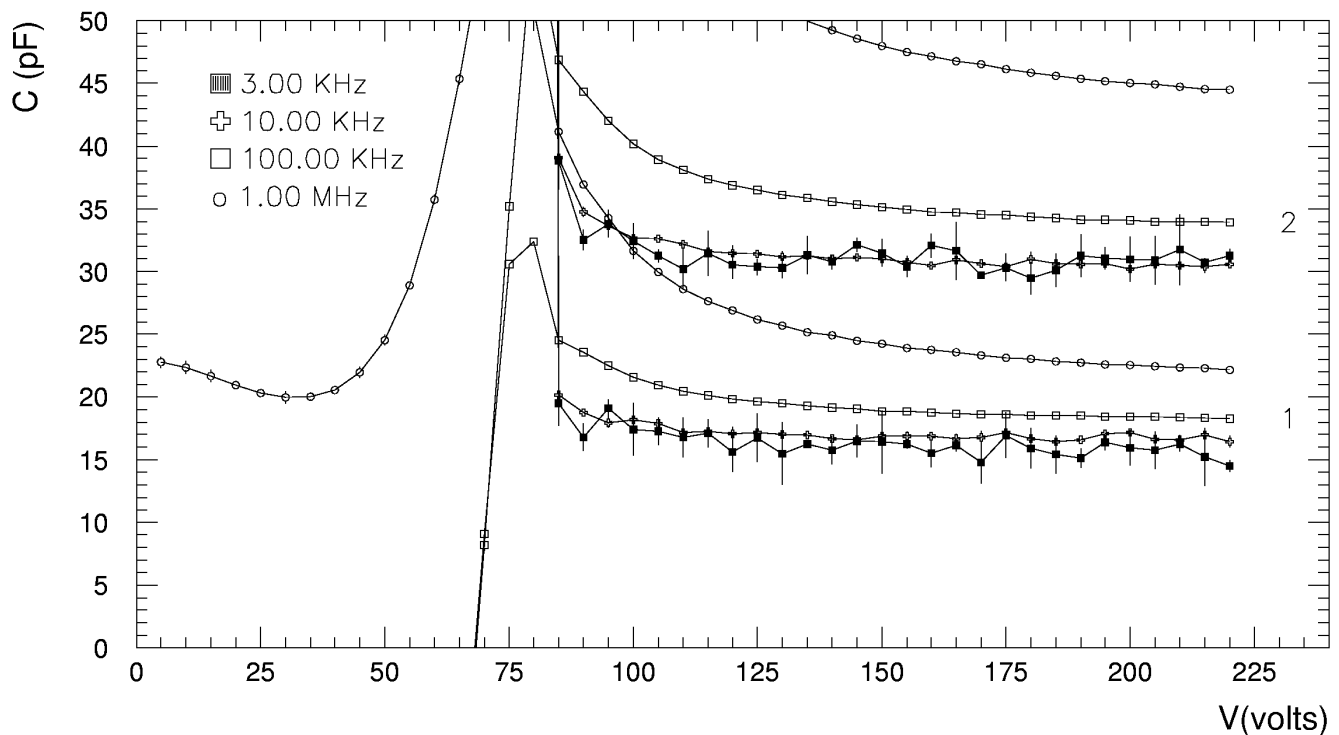


*CERN-EP-99/152

Inter-pixel capacitance of an unirradiated p-spray SSG sensor

Lower curve: 1 nearest neighbor

Upper curve: both nearest neighbors



Temperature dependence of inter-pixel capacitance of irradiated pixel sensors:

